

AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions and listings of claims in the application:

1-12 (Cancelled).

13. (New) A plasma processing apparatus that performs plasma processing on a workpiece placed on an electrode provided inside a processing chamber, comprising:

an electrically conductive ring body encompassing the periphery of said workpiece placed on said electrode;

an electrically insulating ring body encompassing the periphery of said electrically conductive ring body;

a thermal conductivity adjusting member provided between said electrode and said electrically conductive ring body.

14. (New) A plasma processing apparatus according to claim 1, further comprising a means for heat application provided at said electrically insulating ring body.

15. (New) A plasma processing apparatus according to claim 1, wherein a thermal conductivity between said workpiece and said electrode is represented as Q,

wherein an area of a surface of said electrically conductive ring body contacting said plasma is represented as S1,

FINNEGAN
HENDERSON
FARABOW
GARRETT &
DUNNER ^{LLP}

1300 I Street, NW
Washington, DC 20005
202.408.4000
Fax 202.408.4400
www.finnegan.com

wherein an area of a surface of said electrically conductive ring body contacting said electrode is represented as S_2 , and

wherein said thermal conductivity adjusting member achieves a thermal conductivity R express as $R = Q \times S_1/S_2$.

16. (New) A plasma processing apparatus according to claim 1, further comprising a means for pressure application that applies a pressure to said electrically conductive ring body toward said electrode and is capable of adjusting the level of pressure applied to said electrically conductive ring body.

FINNEGAN
HENDERSON
FARABOW
GARRETT &
DUNNER ^{LLP}

1300 I Street, NW
Washington, DC 20005
202.408.4000
Fax 202.408.4400
www.finnegan.com